

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED  
#4  
P.B.



Attorney Docket No.: VL5I-3234 (PHA 780016)

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Group Art Unit: 2763

Examiner: Not yet assigned

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET

The Commissioner of Patents and Trademarks  
Washington, D.C. 20231  
Sir:

## Information Disclosure Statement Submitted Pursuant to 37 C.F.R. 1.97(b)

The citations referenced herein, copies attached, may be material to the examination of the above-identified application and are, therefore, submitted in compliance with the duty of disclosure as defined in 37 C.F.R. 1.56. The Examiner is requested to make these citations of official record in the application.

This Information Disclosure Statement submitted in accordance with 37 C.F.R. 1.97(b) is not to be construed as a representation that a search has been made, that additional items material to the examination of this application do not exist, or that any one or more of these citations constitute prior art under 35 U.S.C. 102.

The Examiner's attention is respectfully directed to the following U.S. Patents:

<u>Pat. No.</u>	<u>Pat. Title</u>	<u>Grant Date</u>
4,253,112	PROCESS FOR AUTOMATIC ALIGNMENT OF TWO OBJECTS TO BE ADJUSTED WITH RESPECT TO ONE ANOTHER	2/24/81
5,760,484	ALIGNMENT MARK PATTERN FOR SEMICONDUCTOR PROCESS	6/2/98
4,880,309	DARK FIELD TARGET DESIGN SYSTEM FOR ALIGNMENT OF SEMICONDUCTOR WAFERS	11/14/89

## Other Documents

PATENT ABSTRACTS OF JAPAN, vol. 017, no. 272 (E-1371), 26 May 1993 (1993-05-26) - JPN 013306 A (Fujitsu Ltd), 22 January 1993 (1993-01-22) abstract; figures

Please direct all correspondence concerning the above-identified application to the following address:

**WAGNER, MURABITO & HAO LLP**  
Two North Market Street, Third Floor  
San Jose, California 95113  
(408) 938-9060

Respectfully submitted,

Date: 10/4/01

By: [Signature]  
John P. Wagner, Jr.  
Reg. No. 35,398

RECEIVED  
OCT 12 2001  
Technology Center 2100

RECEIVED  
OCT 17 2001  
TC 2800 MAIL ROOM

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

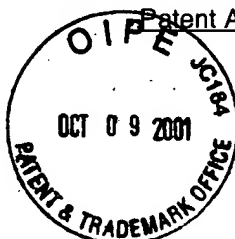
Patent Application

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET



Group Art Unit: 2763

Examiner: Not yet assigned

RECEIVED  
OCT 12 2001  
Technology Center 2100

Form 1449

## U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A	4,253,112	2/24/81	Doemens	358	101	5/21/79
	B	5,760,484	6/2/98	Lee et al.	257	797	2/11/97
	C	4,880,309	11/14/89	Wanta	356	401	4/14/87
	D						
	E						
	F						
	G						
	H						
	I						

## Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	L							
	M							
	N							
	O							
	P							
	Q							
	R							

## Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	S	PATENT ABSTRACTS OF JAPAN, vol. 017, no. 272 (E-1371), 26 May 1993 (1993-05-26) -& JP 05 013306 A (Fujitsu Ltd), 22 January 1993 (1993-01-22) abstract; figures
	T	
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered.  
Include copy of this form with next communication to applicant.

RECEIVED  
OCT 17 2001  
TC 2800 MAIL ROOM

Patent 2763  
2123

Docket No.: VLSI-3234 (PHA 780016)

# Information Disclosure Statement Transmittal

I hereby certify that this transmittal of the below described document is being deposited with the United States Postal Service in an envelope bearing First Class Postage and addressed to the Commissioner of Patents and Trademarks, Washington, D.C., 20231, on the below date of deposit.			
Date of Deposit:	10/4/01	Name of Person Making the Deposit:	Karen Yarr
		Signature of the Person Making the Deposit:	<i>Karen Yarr</i>

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET

Group Art Unit: 2763

Examiner: Not yet assigned



RECEIVED  
OCT 12 2001  
Technology Center 2100

The Commissioner of Patents and Trademarks  
Washington, D.C. 20231  
Sir:

### Information Disclosure Statement Transmittal

Transmitted herewith is the following:

- ..... Formal drawings, totaling ..... sheets.
- ..... Informal drawings, totaling ..... sheets.
- ☒ Certification for PTO Consideration
- ☒ Information Disclosure statement ( 1 sheets)
- ..... Information Disclosure statement and late filing fee
- ☒ Form 1449
- ..... Petition for Extension of Time
- ..... Other: .....

RECEIVED  
OCT 17 2001  
TC 2800 MAIL ROOM

### Fee Calculation (for other than a small entity)

Fee Items	Fee Rate	Total
Petition for Extension of Time (fee calculated elsewhere)	\$ .00	0.00
Information Disclosure Statement, late filing	\$240.00	0.00
Other:		
<b>Total Fees</b>		0.00

### PAYMENT OF FEES

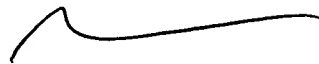
1. The full fee due in connection with this communication is provided as follows:
  - [ ] The Commissioner is hereby authorized to charge any additional fees associated with this communication or credit any overpayment to Deposit Account No.: 23-0085.  
A duplicate copy of this authorization is enclosed.
  - [ ] A check in the amount of \$
  - [X] Charge any fees required or credit any overpayments associated with this filing to Deposit Account No.: 23-0085.

Please direct all correspondence concerning the above-identified application to the following address:

**WAGNER, MURABITO & HAO LLP**  
Two North Market Street, Third Floor  
San Jose, California 95113  
(408) 938-9060

Respectfully submitted,

Date: 10/4/01

By:   
John P. Wagner, Jr.  
Reg. No. 35,398

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED  
OCT 12 2001  
Technology Center 2100

Docket No.: VLSI-3234 (PHA 780016)

I hereby certify that this transmittal of the below described document is being deposited with the United States Postal Service in an envelope bearing First Class Postage and addressed to the Assistant Commissioner for Patents, Washington, D.C., 20231, on the below date of deposit.				
Date of Deposit:	10/4/01	Name of Person Making the Deposit:	Karen Yarr	Signature of the Person Making the Deposit:
			<i>Karen Yarr</i>	

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET

The Assistant Commissioner for Patents  
Washington, D.C. 20231  
Sir:

Certification for PTO Consideration of an Information Disclosure Statement  
(Under 37 CFR §1.97)

Consideration of the enclosed Information Disclosure Statement is requested.

1. This certification is being made for this information disclosure statement  
☒ [ X ] accompanying this certification  
☐ [ ] Filed \_\_\_\_\_

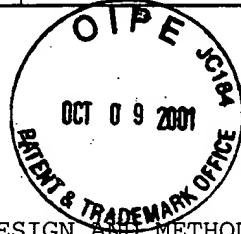
2. I hereby certify that:

- ☒ X Each item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the statement.  
☐ No item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart application, or, to the knowledge of the person signing certification after making reasonable inquiry, was known to any individual designated in §1.56(c) more than three months prior to the filing of the statement.

3. The person making this certification is

- ☒ [ x ] a person who is substantively involved in the preparation or prosecution of the application, and who is associated with the inventor, with the assignee, or with anyone to whom there is an obligation to assign the application (37 C.F.R. 1.56 (c)) and who signs below.
- ☐ [ ] the inventor(s) who signs below
- ☐ [ ] the practitioner who signs below on the basis of the information:  
☐ [ ] supplied by the inventors  
☐ [ ] supplied by an individual designated in § 1.56(c)  
☐ [ ] in the practitioners file

RECEIVED  
OCT 17 2001  
TC 2800 MAIL ROOM



Please direct all correspondence concerning the above-identified application to the following address:


**WAGNER, MURABITO & HAO LLP**  
Two North Market Street, Third Floor  
San Jose, California 95113  
(408) 938-9060

Respectfully submitted,

Date:

10/4/01

By:

  
John P. Wagner, Jr.  
Reg. No. 35,398

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Patent Application

Inventor(s): Hubbard

Serial No.: 09/520,686

Filed: 3/7/00

Title: WAFER TARGET DESIGN AND METHOD FOR DETERMINING CENTROID OF WAFER TARGET



Group Art Unit: 2763

Examiner: Not yet assigned

RECEIVED  
OCT 12 2001  
Technology Center 2100

Form 1449**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A	4,253,112	2/24/81	Doemens	358	101	5/21/79
	B	5,760,484	6/2/98	Lee et al.	257	797	2/11/97
	C	4,880,309	11/14/89	Wanta	356	401	4/14/87
	D						
	E						
	F						
	G						
	H						
	I						

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	L							
	M							
	N							
	O							
	P							
	Q							
	R							

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	S	PATENT ABSTRACTS OF JAPAN, vol. 017, no. 272 (E-1371), 26 May 1993 (1993-05-26) -& JP 05 013306 A (Fujitsu Ltd), 22 January 1993 (1993-01-22) abstract; figures
	T	
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered.  
Include copy of this form with next communication to applicant.

RECEIVED  
OCT 17 2001  
TC 2800 MAIL ROOM